

عنوان مقاله:

Nano Piezoresistive accelerometer Modeling

محل انتشار:

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خلاصه مقاله:

In this paper, behaviour of the piezoresistive picture-frame accelerometer is modeled and studied in the range of medium-high gravity by using the elasticity analysis method (EAM). The model, reviews the effect of applying piezoresistance in two Micro and Nano scales on the sensitivity of accelerometer. According to the results, by using Nano scale piezoresistance instead of micro scale, increased sensitivity of about 2023% is achieved.

کلمات کلیدی:

Modelling; Nano accelerometer; Piezoresistance; Sensitivity

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